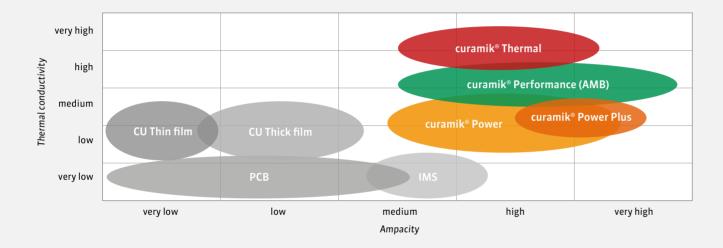






curamik® CERAMIC SUBSTRATES Product Information

Performance overview



curamik® high temperature/high voltage substrates consist of pure copper bonded to a ceramic substrate such as Al₂O₃ (Alumina), AlN (Aluminum Nitride), HPS (ZrO₂ doped) or silicon based Si₃N₄ (Silicon Nitride).

curamik provides two technologies to attach the substrate with the copper. DBC (direct bond copper) – a high temperature

melting and diffusion process where the pure copper is bonded onto the ceramic and AMB (active metal brazing) – a high temperature process where the pure copper is brazed onto the ceramic substrate.

The high heat conductivity of Al_2O_3 (24 W/mK), AIN (170 W/mK) and Si_3N_4 (90 W/mK) as well as the high heat capacity and ther-

curamik® Power



Al₂O₃ ceramic based substrates are standard products with the best price performance ratio. They are mainly used in applications of medium and lower power ranges, such as

- // General Power Electronics
- Concentrated Photovoltaics (CPV)
- // Peltier Elements

curamik® Power Plus



HPS substrates are enhanced in robustness through Zr doped Al₂O₃ ceramic. They are mainly used in applications of medium power ranges, such as

- // Advanced Industrial Applications
- // Automotive Power Electronics

curamik® Thermal



Substrates based on AIN ceramics are used in applications with very high operational voltages and highest power density, such as

- // Traction
- // Smart Grid
- // Industrial High Power Modules
- // Energy

curamik® Performance

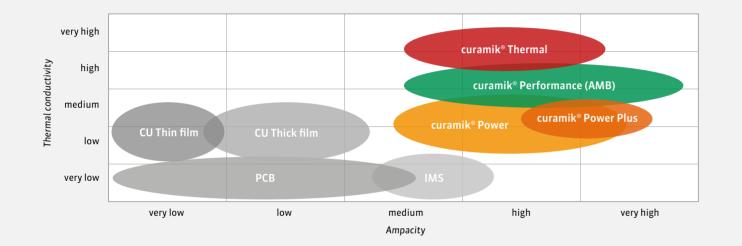


Substrates based on Si₃N₄ ceramics are produced in an AMB process. They are mainly used in applications where a long lifetime, high reliability, and robustness are required and partial discharge should not occur, such as

- / Automotive Power Electronics
- // High Reliability Power Modules
- // Renewable Energy

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melting and diffusion process where the pure copper is bonded onto the ceramic and AMB (active metal brazing) - a high temperature process where the pure copper is brazed onto the ceramic substrate.

The high heat conductivity of Al₂O₃ (24 W/mK), AlN (170 W/mK) and Si₃N₄ (90 W/mK) as well as the high heat capacity and ther-

mal spreading of the thick copper cladding (127 – 800 μm) makes our substrates indispensable to power electronics. The mechanical stress on silicon chips mounted directly on the substrate (Chip on Board) is very low, since the coefficient of thermal expansion (CTE) of the ceramic substrate is better matched to the CTF of silicon compared to substrates using a metal or a plastic basis. Rogers produces high temperature/high voltage substrates in a master card format that measures 5" x 7" and 5.5" x 7.5". The individual parts can be left in the master card format to support more efficient assembly and mounting of components before being separated into individual pieces. We also offer single pieces for single piece assembly.

Advantages:

- Great heat conductivity and temperature resistance for high performance and high temperature applications
- High insulation voltage
- High heat spreading
- Adjusted coefficient of thermal expansion between chip and substrate
- Efficient processing of master cards and single pieces

Available materials

| Al ₂ 0 ₃ | Alumina | curamik® Power |
|--------------------------------|-------------------------------------|----------------------|
| HPS* | Alumina (9% ZrO ₂ doped) | curamik® Power Plus |
| Si ₃ N ₄ | Silicon Nitride | curamik® Performance |
| AIN | Aluminum Nitride | curamik® Thermal |

^{*} The HPS products are subject to patent restrictions in some countries.

Thermal conductivity

| Al ₂ 0 ₃ | 24 W/mK @ 20°C |
|--------------------------------|-----------------|
| HPS | 26 W/mK @ 20°C |
| Si ₃ N ₄ | 90 W/mK @ 20°C |
| AIN | 170 W/mK @ 20°C |

Available thickness combinations DBC

copper thicknesses mm

| | | 0.127 | 0.2 | 0.25 | 0.3 | 0.4 | 0.5 |
|------------------------|------|---------------------------------------|---------------------------------------|---------------------------------------|---------------------------------------|-------|-----|
| ceramic thicknesses mm | 0.25 | Al ₂ 0 ₃ | Al ₂ 0 ₃ HPS | Al ₂ 0 ₃ HPS | Al ₂ 0 ₃ HPS | | |
| | 0.32 | | HPS | Al ₂ 0 ₃ HPS | Al ₂ 0 ₃ HPS | HPS | HPS |
| | 0.38 | AI203 | AI203 | AI203 | AI203 | | |
| | 0.5 | AI203 | AI203 | AI203 | AI203 | AI203 | |
| | 0.63 | Al ₂ 0 ₃ Aln | | |
| | 1.00 | Al ₂ 0 ₃ AlN | | |
| | | | | | | | |

Available thickness combinations AMB

| шш | | copper thicknesses mm | | | |
|-------------|------|--------------------------------|--------------------------------|--------------------------------|--|
| thicknesses | | 0.3 | 0.5 | 0.8 | |
| | 0.25 | Si ₃ N ₄ | Si ₃ N ₄ | | |
| ceramic | 0.32 | Si ₃ N ₄ | Si ₃ N ₄ | Si ₃ N ₄ | |

Note other copper thicknesses on request.

Coefficient of linear thermal expansion (CTE)

| Al ₂ O ₃ | 6.8 ppm/K @ 20°C - 300°C |
|--------------------------------|--------------------------|
| HPS | 7.1 ppm/K @ 20°C - 300°C |
| Si ₃ N ₄ | 2.5 ppm/K @ 20°C - 300°C |
| AIN | 4.7 ppm/K @ 20°C - 300°C |

with copper plating 5% to 60% higher (dependent on copper thickness)

General dimensions

| Total dimensions master card | 138 mm x 190.5 mm ± 1.5% | |
|---------------------------------|---|--|
| Max. useable area | 127 mm x 178 mm ± 0.05% | |
| Copper peeling strength | ≥ 4.0 N/mm @ 50 mm/min for DBC with 0.3 mm Cu-thickness ≥ 10.0 N/mm @ 50 mm/min for AMB with 0.5 mm Cu-thickness | |

Typ. width of / spacing between conductors

| Cu-thickness | width DBC | width AMB |
|--------------|-----------|-----------|
| 0.127 mm | ≥ 0.35 mm | n/a |
| 0.2 mm | ≥ 0.4 mm | n/a |
| 0.25 mm | ≥ 0.45 mm | n/a |
| 0.3 mm | ≥ 0.5 mm | 0.6 mm |
| 0.4 mm | ≥ 0.6 mm | n/a |
| 0.5 mm | ≥ 0.7 mm | 1.0 mm |
| 0.6 mm | ≥ 0.8 mm | n/a |
| 0.8 mm | n/a | 1.2 mm |
| | | |

Surface options

| Platings | Electroless Ni: 3 μm – 7 μm (8% ± 2% P) all-over | |
|------------------|---|--|
| | Electroless Ag: 0.1 μm – 0.6 μm all-over | |
| | Electroless Au Class A: 0.01 - 0.05 μm all-over on Ni | |
| | Electroless Au Class B: 0.03 - 0.13 μm all-over on Ni | |
| Roughness (DCB)* | $R_a \le 3 \mu m$; $R_z \le 16 \mu m$; $R_{max} = 50 \mu m$ | |
| Roughness (AMB)* | Ra ≤ 1.5 μm; Rz ≤ 10 μm; Rmax = 50 μm | |
| | | |

^{*} Lower roughness on request

curamik® CERAMIC SUBSTRATES Technical data sheet





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